

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Matthias FUERTSCH et al.
Serial No. : 10/564,370
Filed : January 11, 2006
For : MICROPUMP HAVING A PUMP DIAPHRAGM
AND A POLYSILICON LAYER
Examiner : Charles Grant FREAY
Art Unit : 3746
Conf. No. : 7784

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL OF REFERENCES AND INFORMATION
DISCLOSURE STATEMENT PURSUANT TO 37 C.F.R. § 1.97(i)

Sir:

We wish to be made of record the following references:

EP0793736 published on September 10, 1997; this document is not available.
However, correspondence WO96/16203 published on May 30, 1996 is provided
herewith;

DE19530736 published on August 14, 1996;

US5487305 published on January 30, 1996;

WO02/23595 published on March 21, 2002,

A. Brown, G. O'Neill, S. Blackstone, "Single-crystal micromachining using multiple
fusion-bonded layers", Pro. SPIE Vol. 4174, pp. 406-415, Micromachining and
Microfabrication Process Technology VI, 08/2000;

C. Gormeley, A. Boyle, V. Srigengan, S. Blackstone, HARM Processing Techniques
for MEMS and MOEMS devices using bonded SOI substrates and DRIE", Proc.

SPIE Vol. 4174, pp. 98-110, Micromachining and Microfabrication Process Technology VI, 08/2000;

J. Bay, O. Hansen, S. Bouwstra, "Micromachined double backplate differential capacitive microphone", J. Micromech. Microeng. 9 (1999), pp. 30-33;

V. Milanovic, G. A. Matus, T.C. Cheng, B. Cagdaser, "Monolithic high aspect ratio two-axis optical scanners in SOI", Int. Conf. on Microelectromechanical Systems, MEMS2003, Kyoto, Japan, pp. 255-258, Jan. 2003;

T.T. Veenstra, J.W. Berenschot, J.G.E. Gardeniers, R.G.P. Sanders, M.C. Elwenspoek, and A. van den Berg, "Use of Selective Anodic Bonding to Create Micropump Chambers with Virtually No Dead Volume", J. Electrochem. Soc., Volume 148, Issue 2, pp. G68-G72 (February 2001);

C. Gui, R.E. Oosterbroek, J.W. Berenschot, S. Schlautmann, T.S.J. Lammerink, A. van den Berg, and M.C. Elwenspoek, "Selective Wafer Bonding by Surface Roughness Control", J. Electrochem. Soc., Volume 148, Issue 4, pp. G225-G228 (April 2001);

The filing of this Information Disclosure Statement shall not be construed as an admission that the information cited is prior art, or is considered to be material to patentability as defined in 37 C.F.R. § 1.56(b).

It is respectfully requested that the reference be placed in the Patent Office file for the above-identified application for interested members of the public in accordance with 37 C.F.R. § 1.97(i).

Respectfully submitted,

Dated: May 7, 2010

By: /Gerard A. Messina/
Gerard A. Messina
Reg. No. 35,952

Kenyon & Kenyon LLP
One Broadway
New York, NY 10004
(212) 425-7200 (telephone)